CEPC Silicon Tracker Progress Report (8)

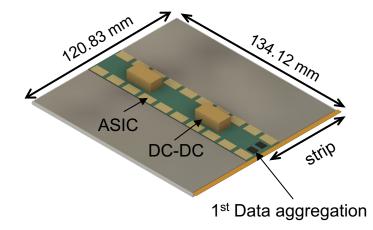
Qi Yan *on behalf of the Silicon Tracker Group* Sep 24, 2024, IHEP

Change of OTK Sensor Power Supply Plan

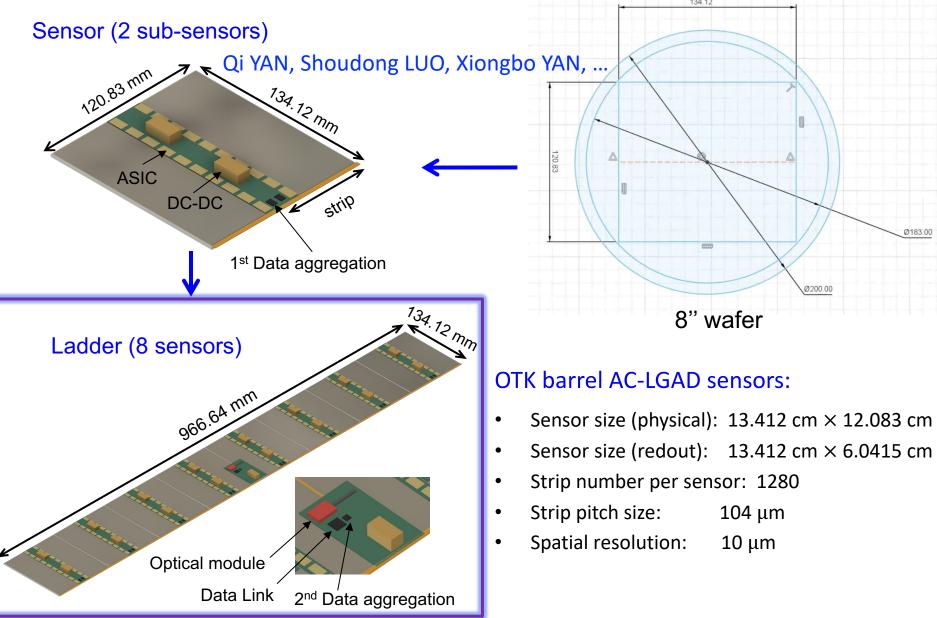
The power consumption of one OTK sensor: 20mW/channel×1280 channel=25.6 W Given that the low voltage (LV) is 1.2 V, the current will be ~21 A. To keep the voltage drop below 0.1 V, the resistance of the pow cable must be 0.005 Ω

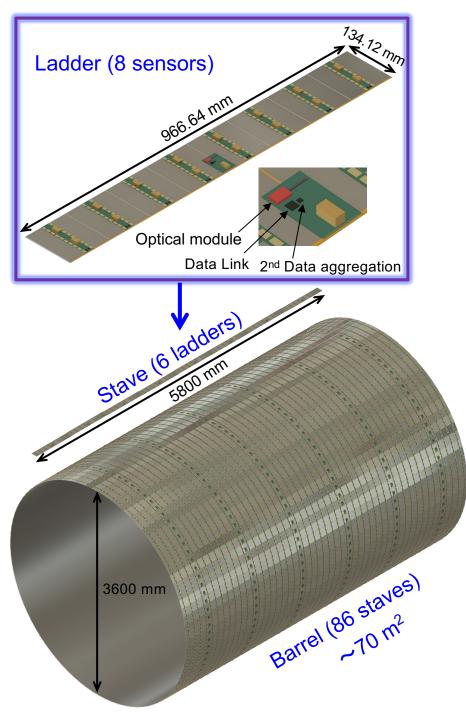
Considering the thickness of power cable in the FPC is 35 μ m, and the length of 1 m, and using Cu with resistivity of $1.75 \times 10^{-8} \Omega \cdot m$, the width of FPC power cable must be >10 cm, which is not acceptable!

In view all the above, transmitting LV through FPC is not feasible. DC-DC converter must be distributed to each sensor.



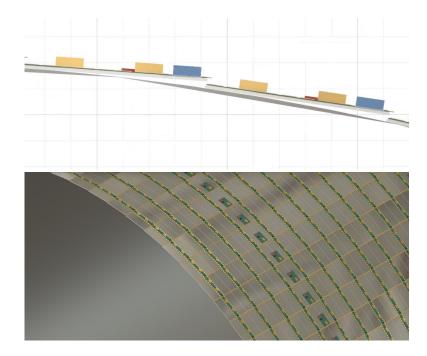
OTK Barrel New Design Plan 1 (One Sensor Per Wafer)



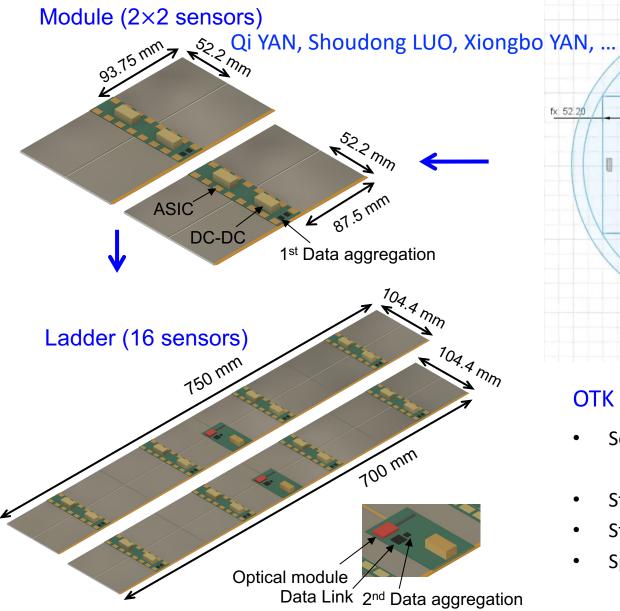


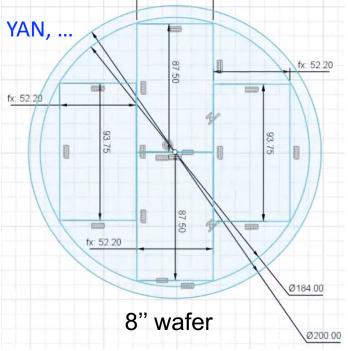
OTK barrel AC-LGAD:

- Sensors per ladder (physical): 8
- Sensors per ladder (redout): 16
- Ladders per stave: 6
- Staves: 86
- Wafer total number: 4128



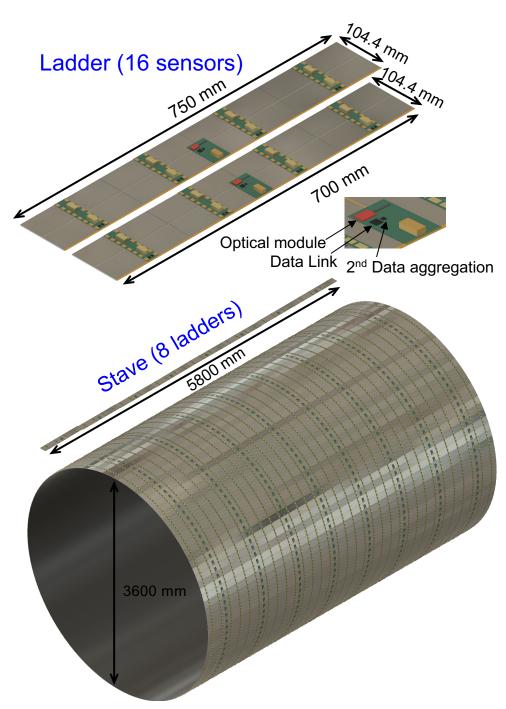
OTK Barrel New Design Plan 2 (Minimal Wafer Usage)





OTK barrel AC-LGAD sensors:

- Sensor size: 9.375 cm × 5.22 cm
 8.75 cm × 5.22 cm
- Strip number per sensor: 512
- Strip pitch size: 100 μm
- Spatial resolution: 10 μm



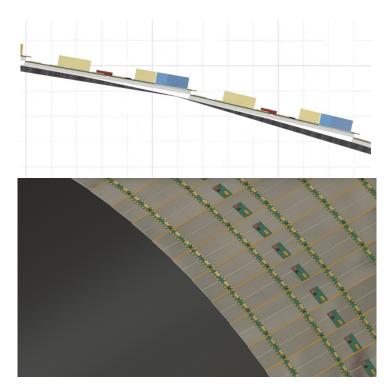
OTK barrel AC-LGAD:

- Sensors per ladder: 16
- Ladders per stave: 8

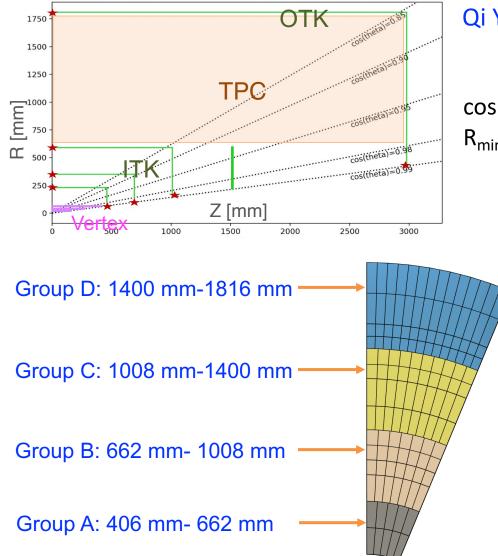
(4 short@middle +4 long@edge)

- Staves: 110
- Wafer total number: 3520

(85% compared with Plan 1)



OTK Endcap Update with Trapezoid Sensors



Qi YAN, Yihan ZHANG, and Shoudong LUO

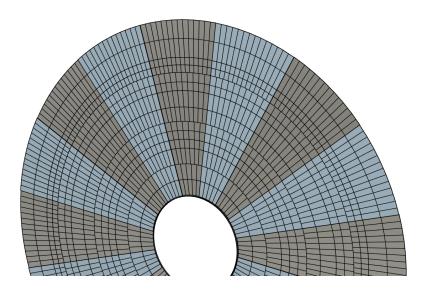
cos(θ)=0.99 corresponds to OTK endcap: R_{min}≈410 mm

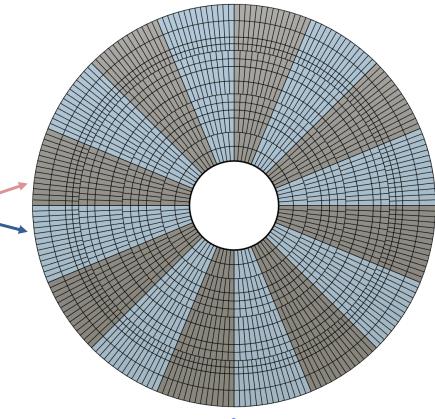
- 14 rings, 4 groups.
- Each group contains 2-4 types of trapezoid sensors, which can be fitted to one silicon wafer.
- Each group of sensors can be aligned to a 1/16 sector.
- The long sensor contains 2 sets of short-strip sensors

Mechanical Assembly Consideration

Qi YAN, Yihan ZHANG, and Shoudong LUO

To simplify installation, adjacent sectors are spaced 3 mm apart.

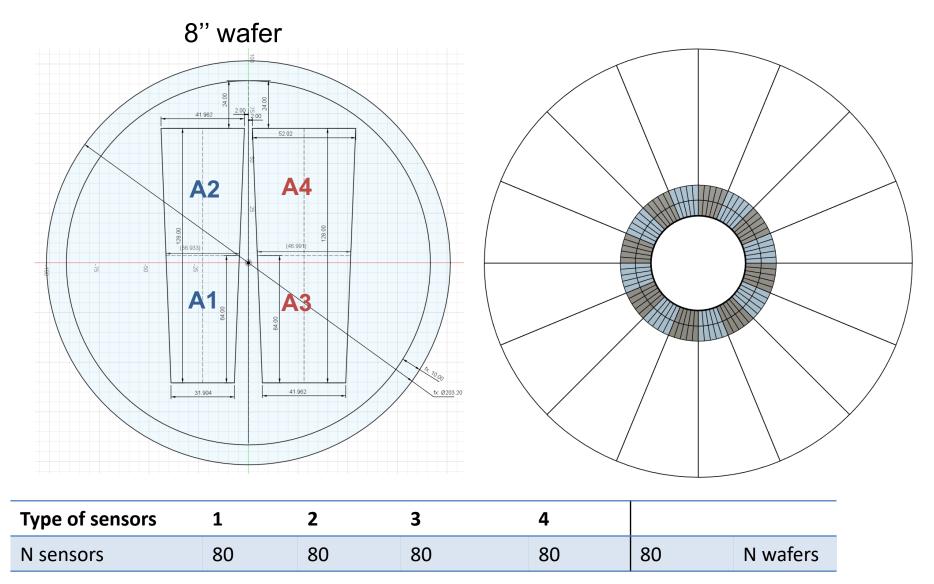




~10 m² per endcap

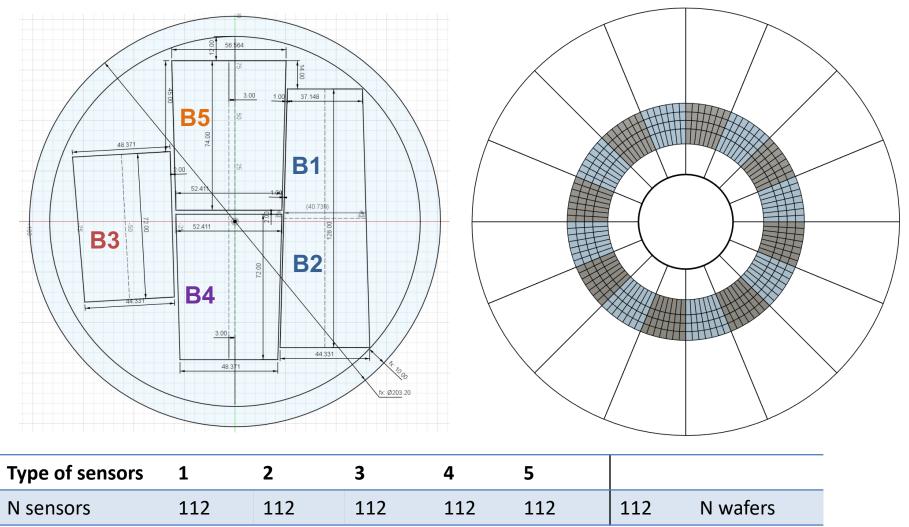
Each sensor has ~3% inactive area, assuming a 300 µm guard ring.100 µm gap between groups considering tolerance can be reserved for assembly.

R: 406 mm-662 mm (Group A)



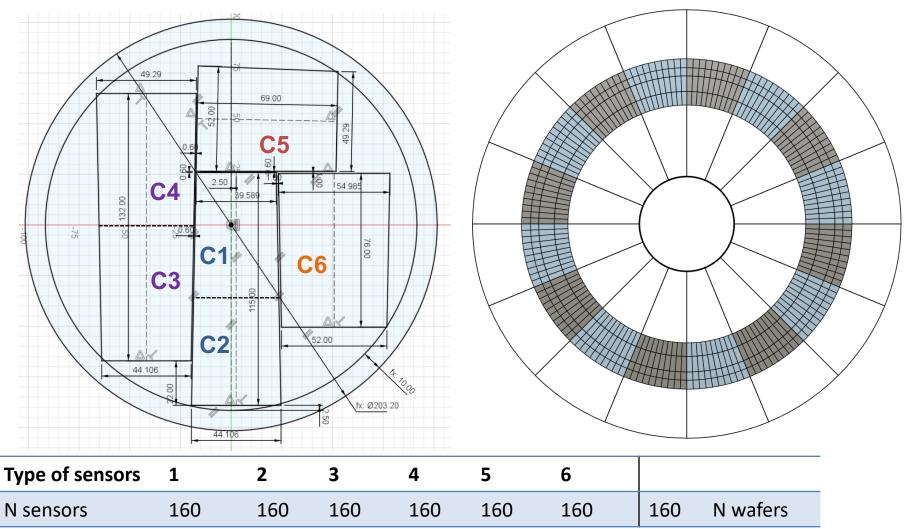
R: 662 mm-1008 mm (Group B)

8" wafer

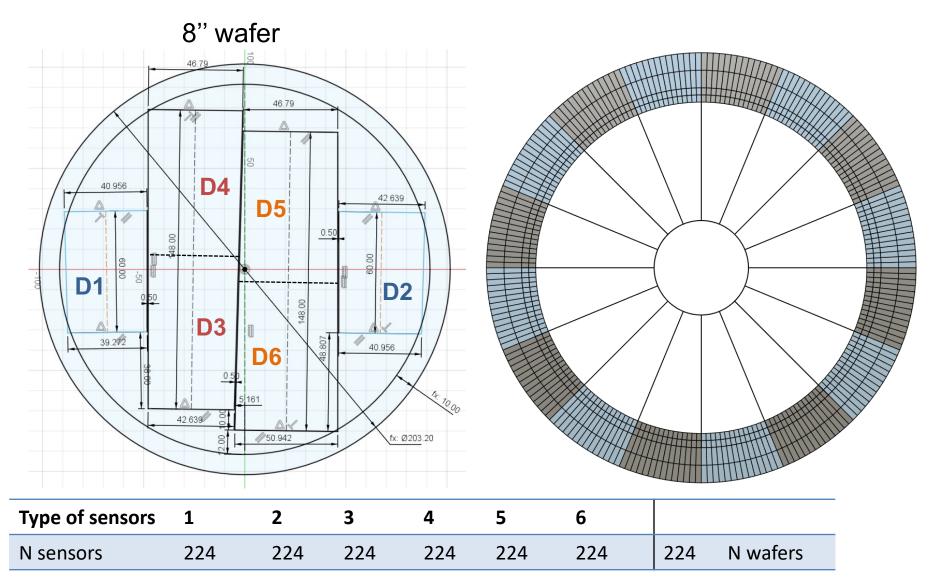


R: 1008 mm-1400 mm (Group C)

8" wafer

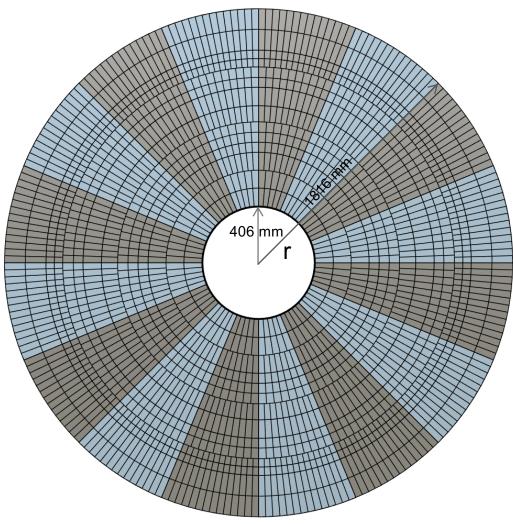


R: 1400 mm-1816 mm (Group D)



OTK Towards TDR

- The power and readout design for the new OTK endcaps will be ready in a few days, similar to the barrels.
- 2) Meanwhile, we will complete the full OTK mechanical design covering both the barrels and endcaps, in a short time. Quan JI will assist in speeding up the mechanical work.



The dE/dx for PID performance using CMOS silicon strips, and design of pixels for ITK endcaps and CMOS strips for ITK barrels, will be discussed in next detector meeting.

